Introduction to scanning electron microscopy microanalysis techniques

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Cursus
Science et génie des matériaux

Sem. Obl.

Type

Language English
Credits 1
Session
Exam Written
Workload 30h
Hours 17
Lecture 9
Exercises 8
Number of positions

Frequency
Only this year

Remarque
Next time: from 11 to 13 December 2019

Summary
Modern Scanning Electron Microscopes, when combined with focused ion beams (Dual beam FIBs), provide a larger number of multimodal imaging and different analytical methods. The course format consists of introductory lectures, lectures on advanced techniques and practical work.

Content
Please find information on the link: https://www.epfl.ch/research/domains/ccmx/courses-and-events/sem2019/

Keywords
Scanning Electron Microscopy; microanalysis, multimodal imaging, analytical methods, chemical analysis.

Resources
Websites
• https://www.epfl.ch/research/domains/ccmx/courses-and-events/sem2019/